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Chemical Vapor Deposition

CVD-XVII
& EUROCVD-17



Sponsored by
The Electrochemical Society & EUROCVD

216th Meeting of the Electrochemical Society
Vienna (Austria), 4-9 October 2009

Scope and Topics

CVD-XVII & EUROCV D-17 will take place within the framework of a well-established sponsorship by the Electrochemical Society (ECS), continuing the long-standing tradition of European CVD Conferences begun in Paris in 1977. The last joint meeting was held in Paris in 2003, while EUROCV D-16 was organized in Den Haag, Netherlands (2006). The *raison d'être* of these Conferences is to highlight common areas of interest and particular challenges for scientists working in the field of chemical vapor deposition and related topics, from both fundamental and applied points of view.

In this context, **CVD-XVII & EUROCV D-17** will provide the opportunity to present **leading research activities in the field from both academic and industrial perspectives**, facilitating interactions and information exchange between people operating in the CVD community and providing opportunities to open up new, intriguing directions for technology transfer.

CVD techniques are versatile and convenient processes for development

and optimization of inorganic, organic and hybrid materials with particular properties. The tremendous growth of related activities in the last decade has been significantly fueled by the possibility of producing nano-organized architectures (such as composites, wires, and nanotubes) and to tailor their characteristics by design according to the specific process paths. As a result, CVD manufacturing of a wide range of products, from heterogeneous catalysts and micromechanical systems, through electronic and optical devices, to smart coatings and chemical sensors, has undergone remarkable development, opening up interesting possibilities for further improvement of functional performance.

Papers describing the use of CVD to deposit **innovative thin films and nanomaterials** are particularly welcome, as well as contributions focusing on **advanced routes** and on the improvement of process control either by theoretical modeling or by the use of advanced characterization techniques.

On this basis, **CVD-XVII & EUROCV D-17** is intended to be

focused on, but not limited to, the following general topics:

- *CVD fundamentals (gas-phase and surface chemistry, reaction mechanisms, kinetics, multi-scale modeling, structure-property relationships)*
- *Novel CVD precursors: design, development and characterization*
- *Innovative CVD strategies (activated processes, plasma-assisted, ALD, iCVD, hybrid strategies)*
- *Non-conventional materials and complex structures by CVD (nanorods and tubes, nanocomposites, nanopillars, nanoparticles and quantum dots)*
- *Process control and diagnostics - in-situ spectroscopy and analytical techniques*
- *Novel processing tools and reactors: CVD from the lab to the fab*
- *Technological applications of CVD techniques (optoelectronics, chemical sensors, energy production, photocatalysis, MEMS devices, etc.)*

Call for papers

Papers accepted for presentation will be published in a proceedings volume that will be available at the meeting. Therefore, **the following deadlines must be strictly met.**

February 13, 2009: submission of titles and short abstracts.

March 6, 2009: notification of abstract acceptance.

April 3, 2009: full abstract due to ECS (**required for paper acceptance!**). Please use the electronic form at <http://www.electrochem.org/meetings>.

April 24, 2009: paper submission opens on ECS web site.

May 22, 2009: Full manuscript due via ECS web site (detailed instructions sent upon abstract acceptance).

July 3, 2009: Revised manuscripts due, if revisions are required.

July 10, 2009: Authors notified of final manuscript acceptance.

Abstract Submission

By **February 13, 2009**, submit a 100-word abstract and full author names, addresses, phone and fax numbers, and e-mail addresses to Davide Barreca (davide.barreca@cnr.it). **The abstracts should be sent only by e-mail as attached Word files.** The official language of the conference is English.

Meeting information

The Symposium will be held in the facilities of the Austria Center Vienna (<http://www.acv.at>). **CVD-XVII & EUROCV D-17** will include all the special features that enable participants to get to know each other in informal, relaxed settings. A special registration package will be available to all attendees, which will include meeting registration, conference proceedings, a banquet, luncheons, and a social excursion. Details of this package will be posted on the Electrochemical Society web page at <http://www.electrochem.org>. Updated information will be available at the EUROCV D conference web site: <http://www.eurocvd17.org>.

